



**EV550719147**

Inventor: **Brian E. Cron**

Title: **Methods for Conditioning Surfaces of Polishing Pads After Chemical Mechanical Polishing**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/075,172**

Filed: **February 13, 2002 [RCE Filed Herewith]**

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the listed reference is prior art.

Citation of this patent is respectfully requested.

Dated: \_\_\_\_\_

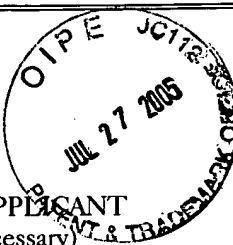
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Respectfully submitted,

By: \_\_\_\_\_

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Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICELIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)ATTY. DOCKET NO.  
MI22-1804SERIAL NO.  
10/075,172APPLICANT  
Brian E. CronFILING DATE  
Feb. 13, 2002 [RCE filed herewith]GROUP  
3723

## U.S. PATENT DOCUMENTS

| Examiner Initial |    | Document Number | Date  | Name             | Class | Subclass | Filing Date If Appropriate |
|------------------|----|-----------------|-------|------------------|-------|----------|----------------------------|
|                  | AA | 6,776,691 B2    | 08/04 | Nishimura et al. |       |          |                            |
|                  | AB |                 |       |                  |       |          |                            |
|                  | AC |                 |       |                  |       |          |                            |
|                  | AD |                 |       |                  |       |          |                            |
|                  | AE |                 |       |                  |       |          |                            |
|                  | AF |                 |       |                  |       |          |                            |
|                  | AG |                 |       |                  |       |          |                            |
|                  | AH |                 |       |                  |       |          |                            |
|                  | AI |                 |       |                  |       |          |                            |
|                  | AJ |                 |       |                  |       |          |                            |

## FOREIGN PATENT DOCUMENTS

|  |    | Document Number | Date | Country | Class | Sub-class | Translation |    |
|--|----|-----------------|------|---------|-------|-----------|-------------|----|
|  |    |                 |      |         |       |           | Yes         | No |
|  | AK |                 |      |         |       |           |             |    |
|  | AL |                 |      |         |       |           |             |    |
|  | AM |                 |      |         |       |           |             |    |

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

|          |                 |  |
|----------|-----------------|--|
|          | AN              |  |
|          | AO              |  |
|          | AP              |  |
| EXAMINER | DATE CONSIDERED |  |

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.